Investigation of Speciation in III-V Wet Etching to Mitigate Hazardous Product Formation

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Objectives

- Significance. Address safety and disposal of III-V materials that could enable faster *n*-type transistors that use less power.
- Predict the species produced by wet etching III-V semiconductors.
 - Use thermodynamic modeling.
 - Vary pH, molarity, solution chemistry.
- Validate models at select process conditions.
 - Measure both gas and liquid phases.
 - Mass balance on group III (Ga and In) and V (As and Sb).
 - Total
 - Species
 - Scale bench top experiments to full wafer.
 - Start with aqueous solutions of HCl and H₂O₂.



ESH Metrics and Impact

Marker	Max 30 day average	Source
Total Toxic Organics	1.37 mg/l	40 CFR 469.24
Arsenic	0.83 mg/l	40 CFR 469.24
pH	6-9	40 CFR 469.24
Compound	Exposure	Hazard
In ₂ O ₃ , In(OH) ₃	Inhalation via Occupational Exposure	Lung Cancer, Pulmonary Alveolar Proteinosis, Emphysema
AsH ₃	Chronic Exposure >0.05 ppm	Anemia, Cardiovascular Disease, Peripheral Neuropathy

Cummings, Kristin J. et al. "Indium Lung Disease." Chest 141.6 (2012): 1512–1521. PMC. Web. 28 Mar. 2015.

Arsine; MSDS No. P-4565-J [online]; Praxair: Danbury Ct, March 23, 2015

Identify Products from III-V Wet Etching

- Define concentrations of relevant reaction products as function of processing conditions including waste disposal.
 - Wet Etching Parameters
 - $[H_2O_2] = 0.0001 8 M$
 - [HCl] = 0.01-2 M
 - Waste treatment may form hazardous species
- Scale species concentrations in gas and liquid phase to identify potential situations that do not meet regulations.
 - Limitations of current hydride sensors.
 - Reports of 97-99% recovery of indium using MRT gels.

Speciation Gives Insight Into Kinetics

- Selectivity for different III-V compounds
 - Total mass balances show selectivity
 - Role of changing group III vs group V atoms
- Etching Rate and Reaction Rate
 - Total Mass Balance can determine etching rate
 - Reaction Rate derivable from Etching Rate
 - Determine reaction order

$$R^{\complement} = k_0 e^{-\frac{E}{RT}} A_{\text{III-V}}^m [\text{HOOH}]^p$$

Thermodynamics Guides Measurement

- Use thermodynamics to predict species in gas and liquid phases for different pairings of III-V material and etching chemistry.
- Close a mass balance on the etching process by measuring total masses of group III and V atoms in gas and liquid.
- Measure partitioning of species in gas and liquid for different pairings of III-V material and etching chemistry.
 - Especially important to measure In in aqueous phase to determine whether both chloride and hydroxide present.

<u>Complete Speciation May Not Be</u> <u>Necessary</u>

- Feedback from industrial liaisons indicates that a complete study of the speciation products is not necessary at this point.
- Initial phase project will focus on liquid/gas partitioning and broad categories of species
 - Hydroxides vs Chlorides
- Initial phase will also examine simple chemistries such as HCl and H_2O_2

Software for Calculations

- Software packages used to predict speciation.
 - PHREEQCi
 - Designed by USGS for aqueous systems.
 - **STABCAL**
 - Commercial
- Both software packages make use of thermodynamic databases or manually entered parameters.
- Validate with experiments.
- Use to guide selection of techniques to measure species concentration.

Example HCl and H₂O₂ System

- HCl (0.01 1.76 M) and H₂O₂ (1.0 E-4 8 M) based solutions are commonly used for etching III-V materials.
 - Characterized by a redox potential in the range of 0.70 1.1 V.
- Potential-pH (Pourbaix) diagrams were constructed for the following conditions.

[In] = 1.0 E-5 M; [Cl⁻] = 0.01 or 1.76 M

pH range of -1 to 7

Potential range of 0 – 2 V

• Distribution-potential diagrams were constructed for the following conditions.

[In] = 1.0 E-5 M; pH=2 or -0.24

Potential range of 0 – 2 V

Solution Potential as a Function of H₂O₂ Concentration



Potential-pH Diagrams In (10⁻⁵ M) – Cl⁻ (0.01 or 1.76 M) – Water System



Distribution of Indium Species as a Function of Solution Potential



Arsenic Distribution in PHREEQCi





• Good agreement between PHREEQCi and diagram from literature.

Smedley, P.I, and D.g Kinniburgh. "A Review of the Source, Behaviour and Distribution of Arsenic in Natural Waters." Applied Geochemistry 17.5 (2002): 517-68. Web.

<u>Measurement Techniques in Vapor and</u> <u>Aqueous Phases</u>

Equipment	Purpose	Detection Range
Differentially Pumped Mass-Spec	Vapor Phase Detection	> 1 ppt sensitivity
ICP-MS	Liquid Phase Detection	< 10 µg/l
ICP-OES	Liquid Phase Detection	> 10 µg/l

Measure Different Oxidation States

Compound	Phase	Detection Method
Aqueous As(III), As(V) species	Liquid	HPLC-ICP-MS
AsH ₃	Vapor	ICP-MS FTIR: 2115.2, 906.75, 1126.42, 999.22 cm ⁻¹



Day, Jason A et al. "A Study of Method Robustness for Arsenic Speciation in Drinking Water Samples by Anion Exchange HPLC-ICP-MS." *Analytical and Bioanalytical Chemistry* 373.7 (2002): 664-68. Web.

Aqueous Indium Expected



Aqueous Arsenic Expected



SRC Engineering Research Center for Environmentally Benign Semiconductor Manufacturing

Total Mass Balance Experiment

- InAs (100)
 - 1x1 cm² samples patterned and unpatterned
- Etching rate
 - Unpatterned
 - Timed submersion in aqueous solutions.
 - [HCl]=0.01 M
 - [H₂O₂]=0.01, 0.1, 1.0 M.
 - No gas phase data.
 - ICP-MS analyzed samples for total masses of In and As
 - Patterned
 - Etch, remove photoresist, and measure amount etched by profilometry.

Total Mass Balance



1:1 Ratio at Different [H₂O₂]



 Species remain in liquid as predicted

[H2O2]	Ratio
0.01	0.97 ± 0.04
0.1	0.99 ± 0.04
1.0	0.94 ± 0.03





Aqueous Arsenic Expected at Neutral pH



Conclusions

- Aqueous species most stable in solution based on thermodynamic model at concentrations and solution potentials of interest.
- Closed total mass balance on InAs(100) etching reaction based on comparison of profilometry and ICP-MS etching rate data.
- In/As = 1:1 in solution suggests all species remain in liquid over range of interest for H₂O₂.

Future Work

- Develop thermodynamic calculations.
 - Expand databases for use in both PHREEQCi and STABCAL.
 - Replicate simulations in both sets of software to ensure continuity between programs.
 - Extend to binary systems
- Start speciation experiments.
 - Complete differentially-pumped mass spec to measure gas phase species.
 - Develop liquid phase separation procedures for III-V etching products.
 - Perform neutralization experiment

Industrial Interactions and Technology Transfer

Industrial liaisons:

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